



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Mamoru NAKASUJI, et al.

Group Art Unit: 2881

Serial No.: 09/891,511

Examiner: Berman, Jack I.

Filed: June 27, 2001

P.T.O. Confirmation No.: 8779

FOR: INSPECTION SYSTEM BY CHARGED PARTICLE BEAM AND METHOD OF
MANUFACTURING DEVICE USING THE SYSTEM

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

September 9, 2004

Applicant hereby Petitions the Commissioner for Patents to extend the time for response to the Office Action dated May 13, 2004 for one month from August 13, 2004 to September 13, 2004.

Attached please find a check in the amount of \$110.00 to cover the cost of the extension for a large entity. In the event that any additional fees are due in connection with this paper, please charge our Deposit Account No. 50-2866.

Respectfully submitted,

WESTERMAN, HATTORI, DANIELS & ADRIAN, LLP


John P. Kong
Attorney for Applicant
Reg. No. 40,054

JKP:kal
1250 Connecticut Avenue, N.W.
Suite 700
Washington, D.C. 20036
(202) 822-1100
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